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5b Data Sheet

CONFIRMATION NO. 8779

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SERIAL NUMBER	FILING DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.
09/891,511	06/27/2001 RULE	438	2812	010819

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** CONTINUING DATA *none*

** FOREIGN APPLICATIONS

JAPAN 2000-193104 06/27/2000
JAPAN 2000-229101 07/28/2000
JAPAN 2000-335934 11/02/2000
JAPAN 2001-11218 01/19/2001
JAPAN 2001-31901 02/08/2001
JAPAN 2001-31908 02/08/2001
JAPAN 2001-33599 02/09/2001
JAPAN 2001-35089 02/13/2001
JAPAN 2001-158662 05/28/2001
JAPAN 2001-162041 05/30/2001
JAPAN 2001-189304 08/22/2001

IF REQUIRED, FOREIGN FILING LICENSE GRANTED

** 08/29/2001

Foreign Priority claimed	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY	SHEETS DRAWING	TOTAL CLAIMS	INDEPENDENT CLAIMS
35 USC 119 (a-d) conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Mot other	JAPAN	50	60	13
Verified and Acknowledged	Examiner's Signature <i>[Signature]</i>				

ADDRESS

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TITLE

Inspection system by charged particle beam and method of manufacturing devices using the system

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